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(Based on PTO 04-07 version)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)		Complete if Known	
		Application Number	10/518,284-Conf. #3519
		Filing Date	September 2, 2005
		First Named Inventor	Peter Hoghoj
		Art Unit	2882
Examiner Name	C. C. G. Kao J. Yun		
Sheet 1 of 2	Attorney Docket Number	XENOCs 3.3-002	

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	AA*	US-5,999,262-A	12-07-1999	Dohschal et al.	
	AB*	US-6,317,483-B1	11-13-2001	Chen	
	AC*	US-5,799,038-A	08-25-1998	Gutman	
	AD*	US-6,278,764	08-21-2001	Barbee, Jr. et al.	
	AE*	US-5,619,548	04-08-1997	Koppel	
	AF*	US-6,041,099-A	03-21-2000	Gutman et al.	
	AG*	US-4,562,583-A	12-31-1985	Hoover et al.	
	AH*	US-5,127,028-A	06-30-1992	Wittry	
	AI*	US-20040096034-A1	05-20-2004	Michaelsen et al.	
	AJ*	US-5,142,561	08-25-1992	Doumas	
	AK*	US-6,285,506-B1	09-04-2001	Chen	
	AL*	US-6,226,349	05-01-2001	Schuster et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ³
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	MM-DD-YYYY			
JY	BA	EP-0115892	08-15-1984	Philips Nv		✓
JY	BB	WO-02/103710-A2	12-27-2002	X-Ray Optical Systems, Inc.		✓
JY	BC	GB-2217036-A	10-18-1989	Rosser		✓
JY	BD	WO-108162 01	02-01-2001	Univ California		✓

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. * CITE NO.: Those application(s) which are marked with an asterisk (*) next to the Cite No. are not supplied (under 37 CFR 1.98(e)(2)(ii)) because that application was filed after June 30, 2003 or is available in the IFV. * Applicant's unique citation designation number (optional). * See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. * Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). * For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. * Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. * Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	CA	NAUDON et al., "New Apparatus for Grazing Reflectometry in the Angle-Resolved Dispersive Mode", J. Appl. Cryst. Vol. 22, Part 5, pp. 460-464, October 1, 1989.	
	CB	M.P. Ulmer, Production and performance of multilayer coated conic sections, Jul 2001, SPIE, Vol. 4498, page 127-133.	
	CC	M.P. Ulmer, The Fabrication of Wolter I multilayer coated optics via electroforming: an update, Jul 1999, SPIE, Vol. 3773, page 113-121.	
	CD	M. Schuster et al., Laterally Graded Multilayer Optics for X-ray Analysis, SPIE, Vol. 3767, Jul 1999, Page 183-198.	
	CE	Romaine et al., Multilayer Optics for Hard X-ray Astronomy, SPIE, Vol. 4138, Nov. 2000, page 120-125.	
	CF	HEADRICK et al., "Multilayer Optics for a Wiggler Beamline (invited), March 2002, Review of Scientific Instruments, Vol. 43, No. 3, p. 1478-1479.	
	CG	G.E. ICE, "Microbeam Forming Methods for Synchrotron Radiation," © 1997	

Examiner Signature 772865	Juric Yun	Date Considered	6-19-07
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